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PATENT
008565-D7213

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

FUKAMI, Teruaki

Serial No: 09/218,997

Filed: December 22, 1998

For: SILICON WAFER STORAGE WATER AND
SILICON WAFER STORAGE METHOD



Art Unit: 1744

Examiner: ~~not assigned~~ Thornton

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to:
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Name

Signature

5/14/99
Date

**TRANSMITTAL OF INFORMATION DISCLOSURE
STATEMENT**

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

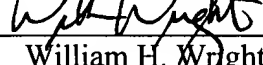
The information disclosure statement submitted herewith is being filed within three months of the filing date of the application or date of entry into the national stage of an international application or before the mailing date of a first Office Action on the merits, whichever event occurs last. 37 C.F.R. § 1.97(b).

I, the person signing below, certify that each item of information contained in the information disclosure statement was cited in the attached communication from a foreign patent office in a counterpart foreign application and that the communication is dated not more than three months prior to the filing of the statement. 37 C.F.R. § 1.97(e)(1).

Please charge any insufficiency of fees necessary to ensure consideration of the information disclosure statement for the above-identified application to Deposit Account No. 12-1820. A copy of this letter is enclosed.

Respectfully submitted,

LOEB & LOEB LLP

By: 
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Date: May 14, 1999

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